[TS03F6]

Nanomanufacturing and Metrology Technologies 6

Date & Time	July 10(Fri.), 2026 / 09:30-11:00
Place	Room 209B
Session Chair(s)	Dr. Yoonkap Kim (GERi)

TS03F6_I_1 ***Invited** 09:30-10:00

Digital Photonic Manufacturing for Multiscale Architected Materials

Seok Kim
(Yonsei University)

TS03F6_I_2 ***Invited** 10:00-10:30

Nonreciprocal Transport in Quantum Matter

Peng Song
(Nanyang Technological University)

TS03F6_O_3 ***YSA Applied** 10:30-10:45

Enhanced Thermoelectric Power Factor of Large-Area MoS_2 through Selective Surface Charge-Transfer Doping

Sooyeon Moon[1,3], Hyejin Jang[1], Kyungjune Cho[2], and Seungjun Chung[3]
([1]Seoul National University, [2]Korea Institute of Science and Technology, [3]Korea University)

TS03F6_O_4 10:45-11:00

Damage-Free, High Density SiN_x Ultrathin Films on Graphite via Plasma-Sequence-Engineered ALD for Robust EUV Pellicles

Hye-Young Kim[1], Sung Kyu Jang[1], Jihun Kim[1,2], Jong-Hyun Choi[1], Hyun-Mi Kim[1], Seul-Gi Kim[1], and Hyeongkeun Kim[1]
([1]Korea Electronics Technology Institute, [2]Sungkyunkwan University)